

FORM PTO-1449 (REV. 6-89)		U.S. DEPARTMENT OF COMMERCE Patent and Trademark Office		Attorney's Name 4765	Serial No. 09/502,534		
INFORMATION DISCLOSURE CITATION				Applicant Dan Meisburger, et al.			
(Use several sheets if necessary)				Filing Date 2/10/00	Group Art Unit 2878		
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
len	A	5 2 8 8 3 6 8	2/22/94	DeMarco et al.	156	643	
len	B	4 6 6 5 3 1 5	5/12/87	Bacchetti et al.	250	492.1	
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes
							No
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)						TC 2800 MAIL ROOM	RECEIVED NOV 13 2000
len	C	Joy, David C. and Joy, Carolyn S., "Dynamic Charging in the Low Voltage SEM", Microscopy Society of America, 1995, Vol. 1, No. 3, pp. 109-112					
len	D	Blais, Phillip D., "Electron-Beam, X-Ray, & Ion-Beam Techniques for Submicrometer Lithographies V", SPIE-The International Society for Optical Engineering, March 11-12, 1986, Vol. 632, pp. 203-209					
len	E	Veneklasen, Lee H., "Scanning Versus Direct Imaging Emission Microscopy", Elsevier Science Publishers B.V., Ultramicroscopy, Vol. 36, Nos. 1-3, May 1991, pp. 63-75					
len	F	Veneklasen, Lee H., "Design of a Spectroscopic Low-Energy Electron Microscope", Elsevier Science Publishers B.V., Ultramicroscopy, Vol. 36, Nos. 1-3, May 1991, pp. 76-90					
len	G	Veneklasen, Lee H., "The Continuing Development of Low-Energy Electron Microscopy for Characterizing Surfaces", Review of Scientific Instruments, Vol. 63, No. 12, December 1992, pp. 5513-5532					
EXAMINER len				DATE CONSIDERED		03-05-01	